



ITW

In re Applicant:

Justin K. Brask et al.

§ Art Unit: 2811

Serial No.: 10/622,955

§ Examiner: Sara W. Crane

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§ Atty Docket: ITL.1021US
P16708

For: Etching Metal Silicides
and Germanides

§ Assignee: Intel Corporation

§

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO PAPER NO. 052005

Sir:

In response to the office action mailed June 3, 2005, please amend the above-referenced patent application as follows:

Date of Deposit: August 3, 2005

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Cynthia L. Hayden

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